

Special Issue

Piezoelectric MEMS/NEMS— Materials, Devices, and Applications

Message from the Guest Editor

The appeal of piezoelectric materials for MEMS/NEMS has been constantly growing, in particular, with the witness of increasing commercial success of piezoelectric MEMS/NEMS devices. The upcoming era of Big Data, sensors, the Internet of Things (IoT), and Artificial Intelligence (AI) has been offering new opportunities and challenges to piezoelectric MEMS/NEMS devices, and we are seeing researchers throughout the world actively tapping into the state-of-the-art micro/nano-fabrication process, promoting advanced integration techniques, and exploring innovative applications to unleash the potential of piezoelectric MEMS/NEMS devices. In this Special Issue, we invite submissions exploring the latest advances in the field of piezoelectric MEMS/NEMS devices.

Guest Editor

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Deadline for manuscript submissions

closed (31 December 2022)



Micromachines

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Impact Factor 3.0
CiteScore 6.0
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